AMENDMENTS TO THE SPECIFICATION:

Please insert the following paragraph before the first line on page 1:

This application is a divisional of Application No. 10/112,046, filed April 1, 2002, the entire content of which is incorporated herein by reference.

Please amend the paragraph beginning at page 9, line 6, as follows:

By putting the reconfiguration element in an active state, shown in Figure 2B, the MEMS switch will display a second type of behaviour based on the changed parameter(s). The reconfiguration beam 211 will bend towards the reconfiguration actuation electrode 215. By bending, the reconfiguration beam 211 will exert a force 231 on the switch beam support 205, bending the switch beam support 205, thus lifting the switching beam 201 further away from the actuation/signal electrode 209, i.e. go increases. The switch beam support 205 has to at least be so ductile that the force 231 will influence the switch beam support 205 and transfer this influence to the switching beam 201. The reconfiguration beam support 213 is preferably of an ~~achor~~ anchor type, i.e. rigid enough to not be influenced to a ~~noticable~~ noticeable extent. If the reconfiguration beam support 213 is of an anchor type, then most of the force generated by the bending of the reconfiguration beam 211 will influence the switch beam support 205. If the reconfiguration beam support 212, 213 is not of an anchor type, then the force 231 will be smaller, which could be desirable is some embodiments.

Please amend the paragraph beginning at page 9, line 24, as follows:

By providing a reconfiguration element according to the invention, and having a ductile switch beam support 204, 205 on a cantilever MEMS switch, it is possible to control go in at least two different steps. If it is possible to bend the reconfiguration beam 210, 211 continuously, then a continuous change of go is attained. A change of go will mainly change the required actuation voltage of the MEMS switch, i.e. according to this embodiment of the invention it is possible to control, dynamically or in a static manner, the required actuation voltage to activate the MEMS switch. This will enable a higher yield of MEMS circuits, since even circuits which do not fall within the required ~~secifications~~ specification from the start can be trimmed by reconfiguration elements. The same MEMS switch can be used in different applications requiring different characteristics/specifications. A transceiver can use the same MEMS switches for both reception and transmission. During reception the reconfiguration element is inactive since there is not much power flowing through a signal electrode of the MEMS switch, and during transmission the reconfiguration element becomes active to allow the MEMS switch to handle more power without becoming unintentionally activated.

Please delete pages 15-18.